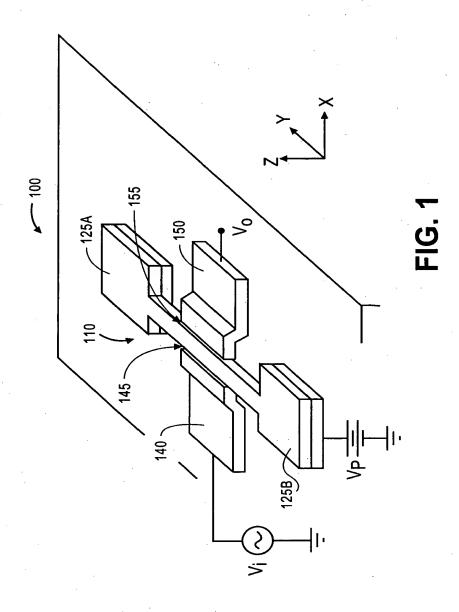
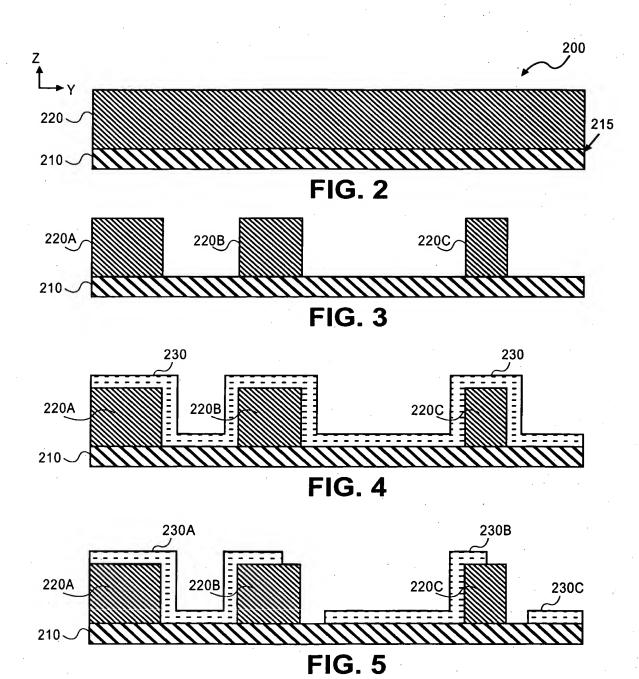
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Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800
Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN MEMS
APPLICATIONS
1st Named Inventor: Qing Ma
Application No.: 09/894,334 Docket No.: 42390P10606
Sheet: 1/11



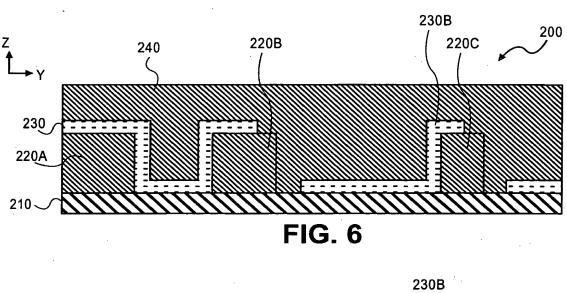
Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN MEMS APPLICATIONS

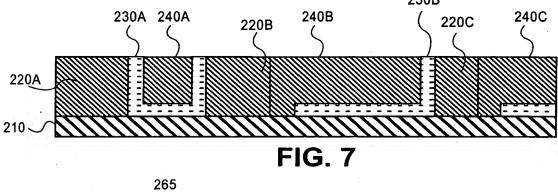
1st Named Inventor: Qing Ma Application No.: 09/894,334 Sheet: 2/11



Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN

MEMS APPLICATIONS
1st Named Inventor: Qing Ma
Application No.: 09/894,334
Sheet: 3/11





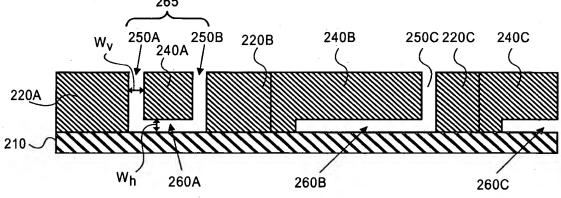
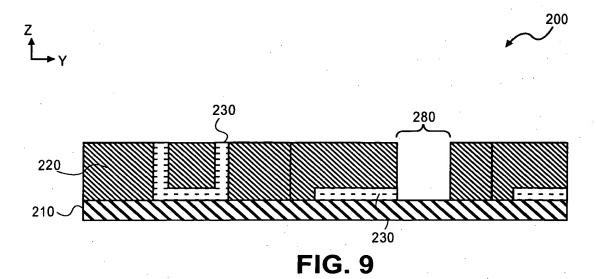


FIG. 8

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800
Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN
MEMS APPLICATIONS
1st Named Inventor: Qing Ma
Application No.: 09/894,334 Docket No.: 42390P10606
Sheet: 4/11



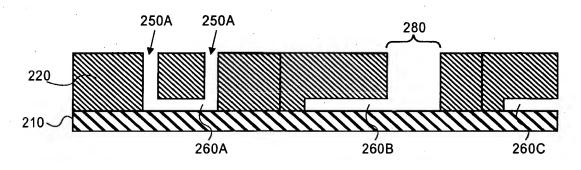


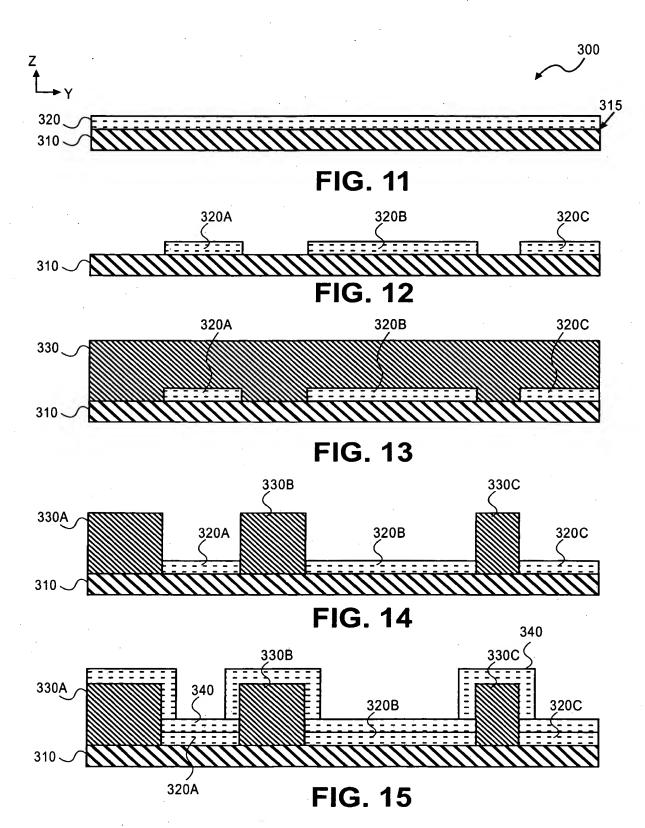
FIG. 10

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN

MEMS APPLICATIONS

1st Named Inventor: Qing Ma Application No.: 09/894,334

Sheet: 5/11



Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN

MEMS APPLICATIONS
1st Named Inventor: Qing Ma
Application No.: 09/894,334
Sheet: 6/11

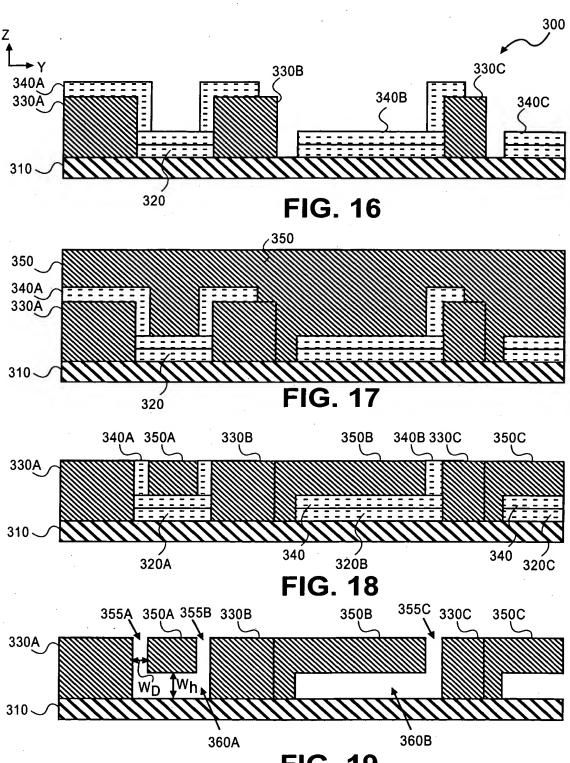


FIG. 19

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN MEMS APPLICATIONS

1st Named Inventor: Qing Ma Application No.: 09/894,334 Sheet: 7/11

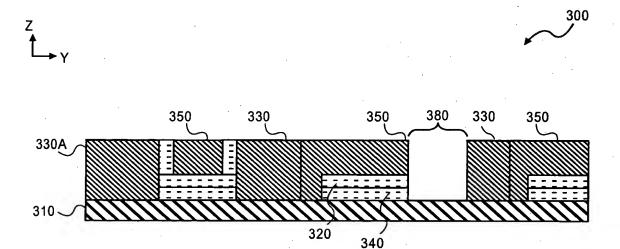


FIG. 20

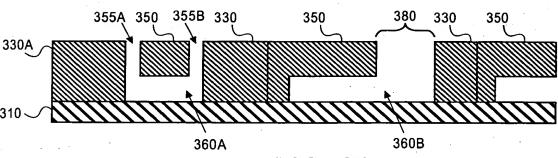


FIG. 21

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN MEMS APPLICATIONS

1st Named Inventor: Qing Ma Application No.: 09/894,334 Sheet: 8/11



FIG. 22

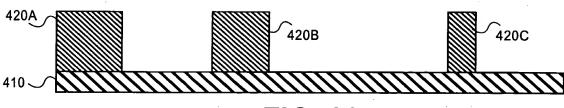


FIG. 23

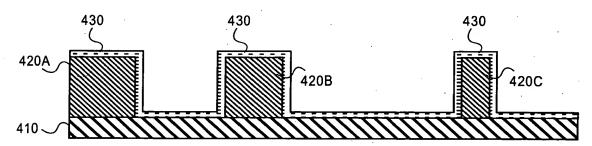


FIG. 24

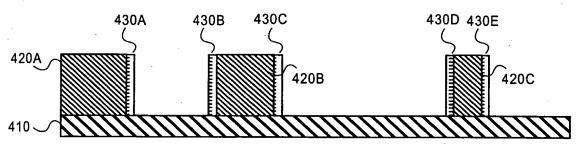


FIG. 25

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN

MEMS APPLICATIONS

1st Named Inventor: Qing Ma Application No.: 09/894,334

Sheet: 9/11



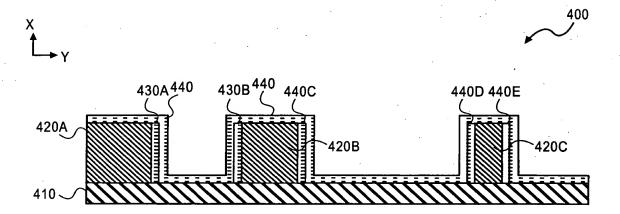
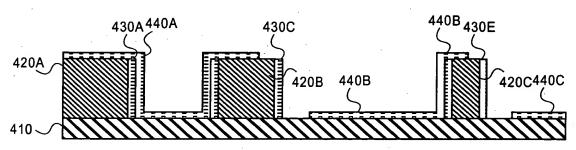


FIG. 26



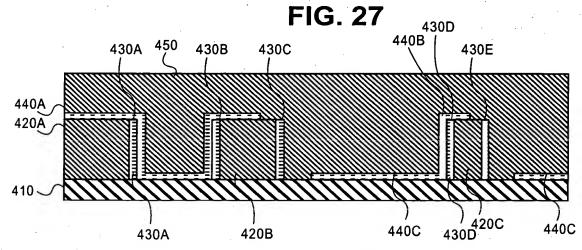


FIG. 28

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800 Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN

MEMS APPLICATIONS

1st Named Inventor: Qing Ma Application No.: 09/894,334

Sheet: 10/11

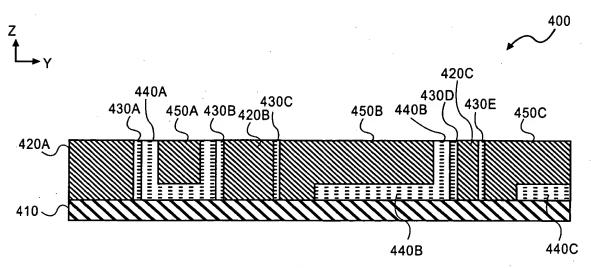


FIG. 29

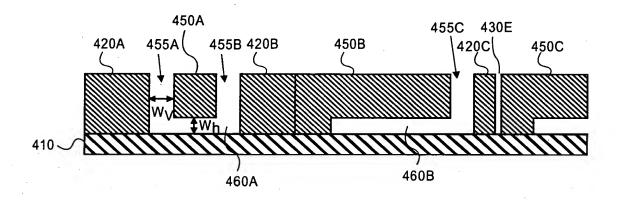
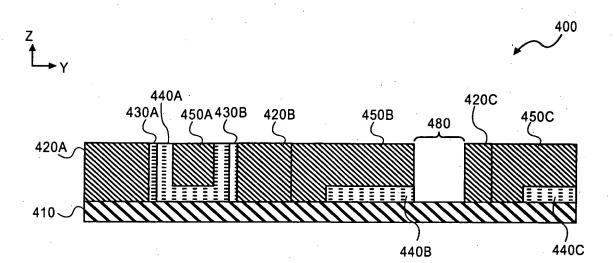


FIG. 30

Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800
Title: SACRIFICIAL LAYER TECHNIQUE TO MAKE GAPS IN MEMS
APPLICATIONS
1st Named Inventor: Qing Ma
Application No.: 09/894,334 Docket No.: 42390P10606
Sheet: 11/11





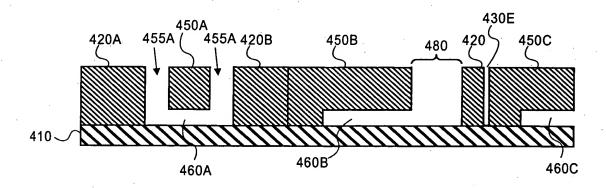


FIG. 32